## Fazhi Song

List of Publications by Year in descending order

Source: https://exaly.com/author-pdf/7928496/publications.pdf Version: 2024-02-01



FAZUL SONC

#	Article	IF	CITATIONS
1	Data-Driven Feedforward Learning With Force Ripple Compensation for Wafer Stages: A Variable-Gain Robust Approach. IEEE Transactions on Neural Networks and Learning Systems, 2022, 33, 1594-1608.	11.3	34
2	Learning Control for Motion Coordination in Wafer Scanners: Toward Gain Adaptation. IEEE Transactions on Industrial Electronics, 2022, 69, 13428-13438.	7.9	33
3	Enhancing Accuracy and Numerical Stability for Repetitive Time-Varying System Identification: An Iterative Learning Approach. IEEE Access, 2020, 8, 25679-25690.	4.2	1
4	Data-Driven Iterative Feedforward Tuning for a Wafer Stage: A High-Order Approach Based on Instrumental Variables. IEEE Transactions on Industrial Electronics, 2019, 66, 3106-3116.	7.9	27
5	An Internal Model Based Iterative Learning Control for Wafer Scanner Systems. IEEE/ASME Transactions on Mechatronics, 2019, 24, 2073-2084.	5.8	19
6	Iterative Learning Identification and Compensation of Space-Periodic Disturbance in PMLSM Systems With Time Delay. IEEE Transactions on Industrial Electronics, 2018, 65, 7579-7589.	7.9	53
7	Intelligent measurement and compensation of linear motor force ripple: a projection-based learning approach in the presence of noise. Measurement Science and Technology, 2018, 29, 064004.	2.6	5
8	Model-Based ILC with a Modified <mml:math <br="" xmlns:mml="http://www.w3.org/1998/Math/MathML">id="M1"&gt;<mml:mi>Q</mml:mi></mml:math> -Filter for Complex Motion Systems: Practical Considerations and Experimental Verification on a Wafer Stage. Complexity, 2018, 2018, 1-11.	1.6	1
9	Modeling and sliding-mode control of wafer stage in lithrography machines. , 2016, , .		0